

Appl. No. 10/707,933
Amdt. dated November 03, 2005
Reply to Office action of October 04, 2005

Amendments to the Claims:

This listing of claims will replace all prior versions, and listings, of claims in the application:

Listing of Claims:

5 Claim 1 (withdrawn): A method of fabricating an organic light emitting display device, the method comprising:

providing a substrate;

forming an organic light emitting unit on the substrate; and

forming a passivation structure layer including organic and inorganic

10 contents over the organic light emitting unit and the substrate,

wherein the passivation layer is formed by supplying one or more source compound of respective ratio varying in time.

Claim 2 (withdrawn): The method of claim 1 wherein forming the
15 passivation structure is performed by a chemical vapor deposition (CVD) process.

Claim 3 (withdrawn): The method of claim 2, wherein the chemical vapor deposition is a plasma enhanced chemical vapor deposition process.

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Claim 4 (withdrawn): The method of claim 1, wherein forming a passivation layer is performed by a sputtering process.

Claim 5 (withdrawn): The method of claim 3, wherein the one or more
25 source compound includes trimethylchlorosilane (TMCS) or hexamethyl disilazane (HMDS).

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Claim 6 (withdrawn): The method of claim 4, wherein the one or more source compound includes an organic source compound and an inorganic source compound.

5 Claim 7 (withdrawn): The method of claim 6, wherein the organic source compound includes PTFE.

Claim 8 (withdrawn): The method of claim 6, wherein the inorganic source compound includes silicon oxide.

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Claim 9 (withdrawn): The method of claim 6, wherein the ratio of the organic source compound decreases in time.

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Claim 10 (withdrawn): The method of claim 6, wherein the ratio of the inorganic source compound increases in time.

Claim 11 (original): An organic light emitting display, comprising:

20 a substrate;
an organic light emitting unit on the substrate, and
a passivation layer covering the organic light emitting unit, wherein
the passivation layer is made of a material including organic and inorganic
contents varying in the thickness of the passivation layer.

Claim 12 (original): The organic light emitting display of claim 11,
25 wherein the organic content is preponderant in a portion of the passivation
layer adjacent to the organic light emitting unit.

Claim 13 (original): The organic light emitting display of claim 11,

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wherein the inorganic content is preponderant in a portion of the passivation layer not in contact with the organic light emitting unit.

Claim 14 (original): The organic light emitting display of claim 11,
5 wherein a thickness of the passivation layer is in a range of about 500 to 5000 angstroms.

Claim 15 (original): The organic light emitting display of claim 11,
wherein the passivation layer includes $\text{SiO}_x\text{C}_y\text{H}_z$, $\text{SiN}_x\text{C}_y\text{H}_z$, or
10 $\text{SiO}_w\text{N}_x\text{C}_y\text{H}_z$ compounds.

Claim 16 (original): The organic light emitting display device of claim 11,
wherein the passivation layer has light transmittance in a range of about 40 to 90%.

15 Claim 17 (original): An organic light emitting display device formed on a substrate, the organic light emitting display device being fabricated by a process comprising:

forming an organic light emitting unit over the substrate; and
20 forming a passivation layer including organic and inorganic contents over the organic light emitting unit, wherein the passivation layer is formed by supplying one or more source compounds of respective ratio varying in time.

25 Claim 18 (original): The device of claim 17, wherein forming a passivation layer is performed by a chemical vapor deposition.

Claim 19 (original): The device of claim 18, wherein the chemical vapor

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deposition is a plasma enhanced chemical vapor deposition.

Claim 20 (original): The device of claim 17, wherein forming a passivation layer is performed by a sputtering process.

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Claim 21 (original): The device of claim 19, wherein the one or more source compound includes trimethylchlorosilane (TMCS) or hexamethyl disilazane (HMDS).

10 Claim 22 (original): The device of claim 20, wherein the one or more source compound includes an organic source compound and an inorganic source compound.

15 Claim 23 (original): The device of claim 22, wherein the organic source compound includes PTFE.

Claim 24 (original): The device of claim 22, wherein the inorganic source compound includes silicon oxide.

20 Claim 25 (original): The device of claim 22, wherein the ratio of the organic source compound decreases in time.

Claim 26 (original): The device of claim 22, wherein the ratio of the inorganic source compound increases in time.

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